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Effects of post-annealing duration on the properties of β -Ga₂O₃ thin films prepared by spray pyrolysis

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ABSTRACT

The post-annealing duration dependence of structural and optical properties of polycrystalline β -Ga₂O₃ thin films fabricated on sapphire (Al₂O₃) substrate via the spray pyrolysis method are presented. Extending the annealing time for fixed temperature 900 °C from 1 to 2 h improves crystallinity of the films, as evidenced by an increase in the average grain size approximately from 8 to 14 nm, a reduction in the full width at half maximum of the 202 β -Ga₂O₃ diffraction peak from 0.43 to 0.29°. However, extending the post-annealing duration to 3 h induces excessive grain coarsening into island-like crystalline domains. These findings demonstrate that for the chosen experimental conditions, a 2-hour annealing at 900 °C represents an optimum for achieving relatively smooth and solid β -Ga₂O₃ films while balancing crystallinity and film homogeneity.

KEYWORDS

Ga₂O₃ film • spray pyrolysis • sol-gel • post-anneal • duration

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Introduction

Gallium oxide (Ga₂O₃), particularly its thermodynamically stable monoclinic β -phase, emerged as a promising ultra-wide bandgap semiconductor for next-generation power electronics and deep-ultraviolet (UV) optoelectronic devices [1]. With a bandgap of ~4.9 eV, β -Ga₂O₃ exhibits exceptional properties, including a high breakdown electric field (8 MV/cm), Baliga's figure of merit (BFOM = $\varepsilon \cdot \mu \cdot E_c^3$, where ε is relative dielectric constant, μ is electron mobility and E_c is critical electric field) (3444), and thermal stability up to its melting point (~1795 °C) [2–4]. These characteristics position Ga₂O₃ as a superior alternative to the conventional semiconductors like SiC and GaN in high-voltage, high-



temperature applications such as solar-blind photodetectors, Schottky diodes, and MOSFETs [1,2]. However, the performance of β -Ga₂O₃ thin films is critically dependent on their crystallinity, stoichiometry, and defect density, which are strongly influenced by synthesis methods and post-processing.

Thin-film fabrication techniques for β -Ga₂O₃ include molecular beam epitaxy (MBE) [5], pulsed laser deposition (PLD) [6], chemical vapor deposition (CVD) [7], metalorganic vapor-phase epitaxy (MOVPE) [8], halide vapor phase epitaxy (HVPE) [9], and radio frequency magnetron sputtering (RFMS) [10,11]. While these methods yield high-quality epitaxial layers, they suffer from limitations such as high equipment costs, complex vacuum requirements, and limited scalability. In contrast, sol-gel methods [12,13] like spray pyrolysis [14,15] offer cost-effective, scalable alternatives. The sol-gel technique excels in molecular-level homogeneity and precise doping control, enabling uniform incorporation of dopants such as Al [16] or Sn [17] to tailor optical and electrical properties. Spray pyrolysis, on the other hand, combines simplicity with industrial scalability, allowing large-area deposition at atmospheric pressure.

Post-annealing is a critical step in optimizing the structural and functional properties of solution-processed Ga₂O₃ films [18,19]. Thermal treatment facilitates the decomposition of organic residues, enhances crystallinity by promoting phase transitions, and mitigates defects such as oxygen vacancies [20,21]. This work investigates the effects of post-annealing duration on the properties of β -Ga₂O₃ thin films fabricated via spray pyrolysis method on sapphire substrate. By correlating annealing time with structural evolution, surface morphology, and optoelectronic performance, we aim to establish optimal processing parameters for high-performance devices.

Materials and Methods

β -Ga₂O₃ thin films were synthesized on (0001)-oriented sapphire (Al₂O₃) substrate via a particular variant of sol-gel technique, namely, spray pyrolysis method. The precursor solution was formulated using gallium nitrate hydrate [Ga(NO₃)₃·8H₂O, 99.9 %, Lankhit] dissolved in 2-methoxyethanol [C₃H₈O₂, 99.5 %, Leap Chem], serving as the solvent. Monoethanolamine (MEA) [C₂H₇NO, 99.5 %, Vekton] was introduced as a stabilizer to ensure solution homogeneity and prevent premature precipitation. The molar concentrations of both gallium nitrate and 2-methoxyethanol were maintained at 0.25 mol/L, with a 3:1 molar ratio of gallium nitrate to MEA. The mixture was magnetically stirred at 60 °C for 1 h to achieve a pale yellow, transparent and stable sol. Prior to deposition, the (0001) sapphire substrate underwent ultrasonic cleaning in sequential baths of isopropanol and deionized water (10 min each) to remove organic contaminants and particulate matter.

The spray pyrolysis setup for Ga₂O₃ thin film fabrication has been described in detail in our previous work [14]. Figure 1 illustrates the preparation workflow. The sol was sprayed onto substrates mounted on a heating stage maintained at 140 °C. Following solvent evaporation, the samples were transferred to a preheated muffle furnace and pre-annealed at 500 °C for 10 min under ambient air atmosphere. This deposition-pre-annealing cycle was repeated 30 times to achieve the desired film thickness. After fabrication, the samples were subjected to post-annealing in the same muffle furnace

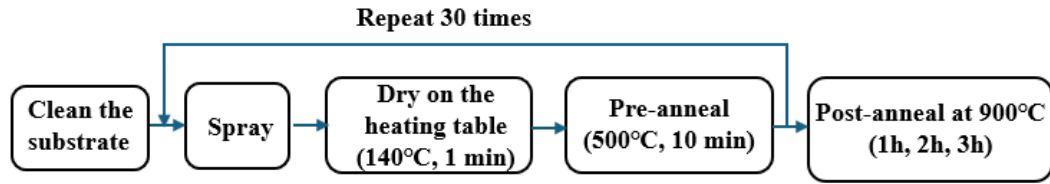


Fig. 1. The workflow of Ga₂O₃ films fabricated by spray pyrolysis

at 900 °C (this temperature corresponds to experimental results published in [21,22]) in air with varying durations of 1, 2, and 3 h.

The crystal structure of the samples was characterized using a Rigaku Ultima IV X-ray diffractometer (XRD) with Cu-K α radiation ($\lambda = 0.15418$ nm). XRD patterns were acquired in the 2θ angular range of 25 to 70° at a scanning rate of 0.5°/min.

The average crystallite size, representing the coherent scattering domain, was determined through Halder-Wagner analysis [23,24] of the XRD data using the following relation:

$$\left(\frac{\beta^*}{d^*}\right)^2 = \frac{1}{t} \times \left(\frac{\beta^*}{d^{*2}}\right) + \left(\frac{\varepsilon}{2}\right)^2, \quad (1)$$

where $\beta^* = \frac{\beta \cos \theta}{\lambda}$, $d^* = \frac{2 \sin \theta}{\lambda}$, β denotes the experimental FWHM (in radians), $\lambda = 0.15418$ nm (Cu-K α radiation wavelength), ε quantifies the micro-strain within crystallites, t corresponds to the average crystallite size.

The surface morphology of the films was characterized using a TESCAN Mira 3 scanning electron microscope (SEM). For quantitative surface roughness analysis, a Veeco Dimension 3100 atomic force microscope (AFM) was employed to measure the root-mean-square (RMS) roughness and map nanoscale topographic features.

The optical properties of the β -Ga₂O₃ thin films were investigated through transmittance spectroscopy and Tauc plot analysis [25]. Optical transmission spectra were acquired in the 200–850 nm wavelength range using a PerkinElmer Lambda 950 UV-Vis-NIR spectrophotometer, with (0001)-oriented sapphire substrates serving as optical windows. Film thickness was determined via cross-sectional SEM imaging. The optical bandgap (E_g) was calculated using the Tauc relation [25]:

$$(\alpha h\nu)^2 = A(h\nu - E_g), \quad (2)$$

where α is the absorption coefficient, $h\nu$ represents photon energy, and A is a proportionality constant.

The influence of post-annealing temperature on surface morphology and optoelectronic properties was systematically evaluated through comparative analysis of structural and optical data.

Results and Discussion

Figure 2 shows the XRD spectra of β -Ga₂O₃ films post-annealed at 900 °C for 1, 2, and 3 h. Four significant reflection peaks are observed at 30.2, 31.6, 59.3, and 64.7°, corresponding to the (400), ($\bar{2}$ 02), ($\bar{6}$ 03), and ($\bar{7}$ 12) crystallographic planes of crystallites in β -Ga₂O₃ polycrystalline film, respectively. With the increase of post-annealing duration, the intensity of the $\bar{2}$ 02 peak is significantly enhanced and its FWHM decreases, while the other main peaks do not change significantly. This selective enhancement of the

contribution of ($\bar{2}02$) orientation can be attributed to the synergistic effect between substrate-induced epitaxial orientation and thermally activated grain reorganization. The (0001) surface of sapphire substrate has a hexagonal close-packed structure and has a template effect, which is conducive to the growth of β -Ga₂O₃ grains along a specific crystallographic direction. The ($\bar{2}02$) facet of β -Ga₂O₃ may show good lattice matching with the substrate, thus minimizing the interface energy and promoting the preferred orientation during post-annealing.

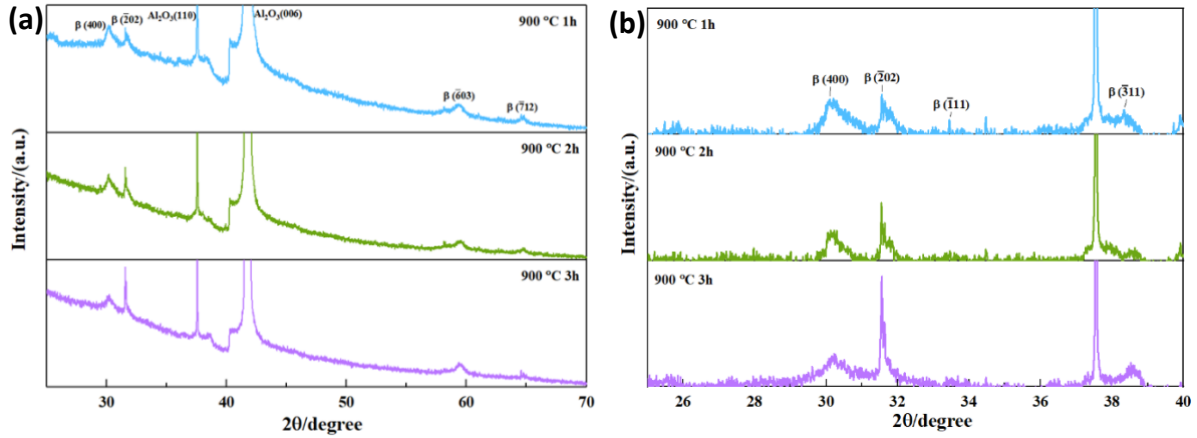


Fig. 2. XRD patterns of β -Ga₂O₃ thin films post-annealed at 900 °C for durations of 1, 2, and 3 h (a), detailed patterns (b), compared with ICDD reference data (PDF 00-041-1103)

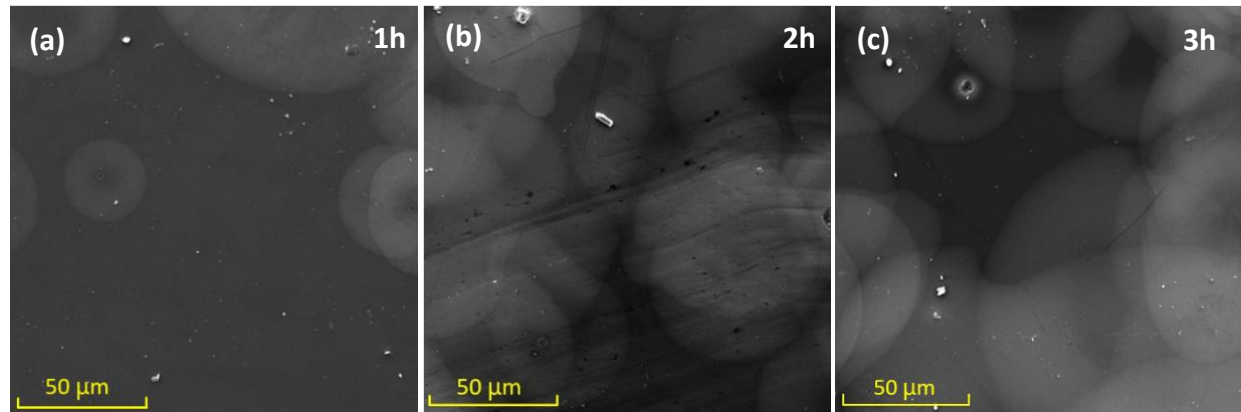
Table 1 summarizes the analysis of diffraction peaks for β -Ga₂O₃ thin films post-annealed at 900 °C for 1, 2, and 3 h. Initially, increasing the annealing duration from 1 to 2 h resulted in a reduction of the full width at half maximum (FWHM) for $\bar{2}02$ peak from 0.43 to 0.29°, accompanied by an increase in average crystallite size from 8.15 to 14.06 nm. This behavior is consistent with enhanced crystallinity and grain coarsening, aligning with classical Ostwald ripening [26], where smaller grains dissolve to supply larger ones, thereby reducing lattice defects and micro-strains. However, extending the annealing time to 3 h further reduces the full width at half maximum (FWHM) to 0.13°, while decreasing the average crystallite size to 11.44 nm. This behavior of the average grain size contradicts the traditional mechanism of nucleation during film crystallization from the amorphous state. Similar effects were observed in other studies [21,27]. In part, this behavior of the grain size can be explained by processes similar to sintering, when additional formation of small grains occurs in the pores between large grains. This can lead to a decrease in the average grain size at a certain stage. Another reason may be the diffusion of aluminum from the substrate, which is observed at temperatures of 900–1000 °C [27,28]. Due to diffusion, a double solid solution (Al_xGa_{1-x})₂O₃ can form in the region close to the substrate, which can also lead to a decrease in the average grain size [29]. However, these hypotheses require verification and confirmation by independent experiments, as well as the dependence of the grain size on the annealing time.

Figure 3 shows top-view SEM images of β -Ga₂O₃ films post-annealed at 900 °C for 1, 2, and 3 h, showing the evolution of the film surface morphology and grain structure under different heat treatment durations. For the sample post-annealed for 1 h (Fig. 3(a)), the film surface is relatively smooth and uniform, and the grains are small and

Table 1. Diffraction peak analysis of β -Ga₂O₃ films with post-annealing temperature of 900 °C and time of 1, 2, and 3 h

Duration, h	FWHM of $\bar{2}02$ peak, °	Average crystallite size, nm
1	0.43	8.15
2	0.29	14.06
3	0.13	11.44

loosely distributed. This indicates that the grain growth is limited in the initial stage of post-annealing because the thermal energy is insufficient for significant atomic diffusion. When the time is extended to 2 h (Fig. 3(b)), the grain density and uniformity are significantly improved, and directional texture appears on the surface. This texture may be aligned with the crystal plane orientations, reflecting the enhancement of atomic mobility and stress relaxation during long post-annealing. For the sample post-annealed for 3 h (Fig. 3(c)), the grain clusters are significantly coarsened to form irregularly sized crystal islands, and the directional texture disappears, which is the result of the combined effects of competitive grain growth mechanisms or local strain redistribution.

**Fig. 3.** SEM top-view images of β -Ga₂O₃ films post-annealed at 900 °C for (a) 1, (b) 2, (c) 3 h

Side-view SEM images of β -Ga₂O₃ films post-annealed at 900 °C for 1, 2, and 3 h are shown in Fig. 4. The thickness of all samples is from 1 to 1.1 μ m, demonstrating that the annealing time has little effect on the film thickness. For the sample post-annealed for 1 h (Fig. 4(a)), the film exhibits a relatively discontinuous layered structure. The grain boundaries are not resolved and the interface between the film and the substrate is slightly rough, indicating incomplete crystallization and limited atomic mobility in the initial stage of post-annealing. This is because the oxygen vacancy compensation effect is stronger than grain growth in a shorter post-annealing time, and insufficient stored thermal energy will limit the complete densification of the film. When the post-annealing time is increased to 2 h (Fig. 4(b)), a more uniform and continuous film cross section structure is observed, accompanied by neatly arranged columnar grains, indicating that atomic diffusion and micro-stress relaxation are enhanced. For the 3 h post-annealed sample (Fig. 4(c)), the columnar grains evolved into larger irregularly shaped domains. This overgrowth and partial structural degradation indicate that the grain growth mechanism shifted from controlled grain growth to competitive crystallization, and excessive thermal exposure led to local micro-strain accumulation.

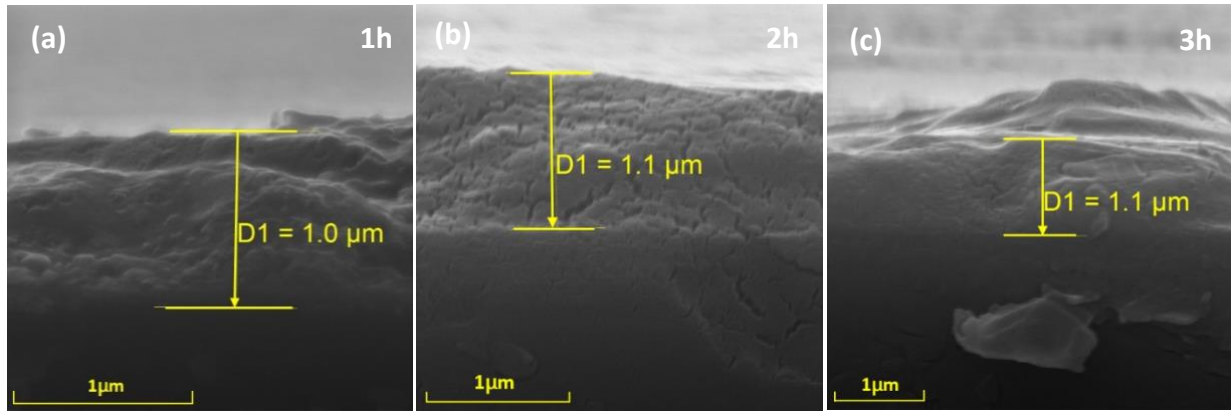


Fig. 4. SEM side-view images of β -Ga₂O₃ films post-annealed at 900°C for (a) 1, (b) 2, (c) 3 h

The two-dimensional AFM images ($1 \times 1 \mu\text{m}^2$) of β -Ga₂O₃ films with different post-annealing durations were analyzed using AFM. As shown in Fig. 5, the surface of the film post-annealed for 1 h is smooth and uniform, with sparse grain distribution and the RMS roughness of 0.94 nm. When the post-annealing duration is extended to 2 h, a significant increase in grain density and size is observed, and the closely packed grains coalesce into a continuous and dense film structure. RMS roughness corresponding to this morphological transformation increases to 1.87 nm. This result is consistent with the increase in the average grain size (see Table 1). Further extending the post-annealing duration to 3 h will form heterogeneous crystal islands of various sizes, and the RMS roughness increases significantly to 2.54 nm. This change is due to thermally driven atomic reorganization. Initially, extending the post-annealing duration is beneficial for the migration of gallium and oxygen atoms to energetically favorable lattice positions, thereby enhancing the densification and crystallinity of the film [30]. However, over-annealing will destroy this balance. This process leads to non-uniform grain growth and competitive crystallization, which increases surface roughness, size differences, and spatial inhomogeneity of grain distribution. Therefore, prolonged thermal exposure can compromise the homogeneity of the structure.

Figure 6 shows the transmittance and estimated band gap of β -Ga₂O₃ films post-annealed at 900 °C for 1, 2, and 3 h. The transmittance of the samples is about 90 % in the 300–850 nm range and has sharp absorption band edges near 250 nm. As the post-annealing

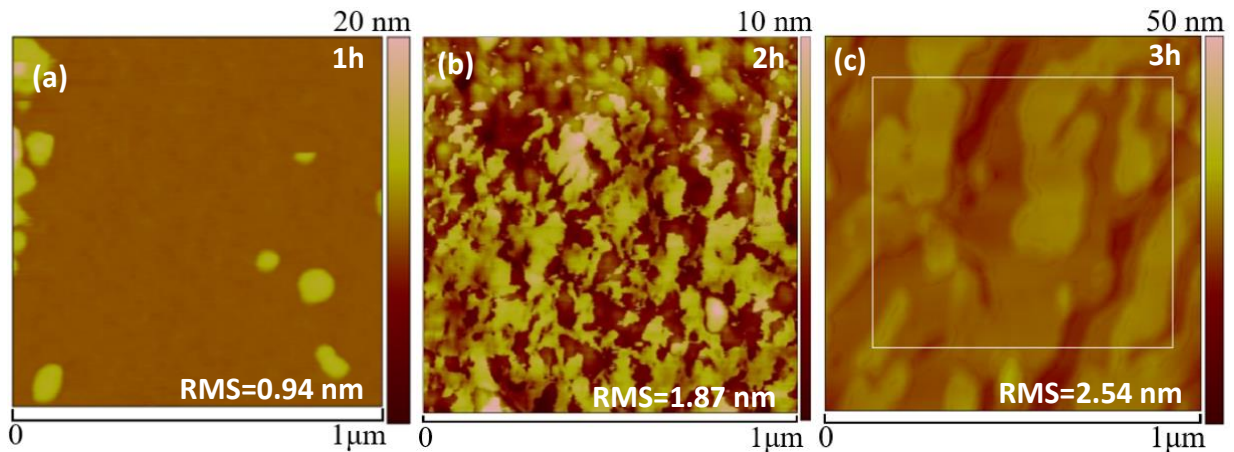


Fig. 5. AFM images of β -Ga₂O₃ films post-annealed at 900 °C for (a) 1, (b) 2, (c) 3 h

time increases, the measured optical band gap values are 4.98, 4.93, and 4.95 eV. The change in the band gap width may be associated with the corresponding changes in the micro-stresses in the film, discussed above. Concurrently, the extended post-annealing duration can facilitate diffusion-driven incorporation of Al³⁺ ions from the (0001) Al₂O₃ substrate into Ga³⁺ lattice positions within the β -Ga₂O₃ lattice sites. This may lead to the formation of a double solid solution of (AlGa)₂O₃ in the near-substrate region, the band gap width of which is larger than that of gallium oxide, proportional to the aluminum content [31]. However, the observed variations in the band gap width are too small to confidently draw conclusions about any noticeable trend.

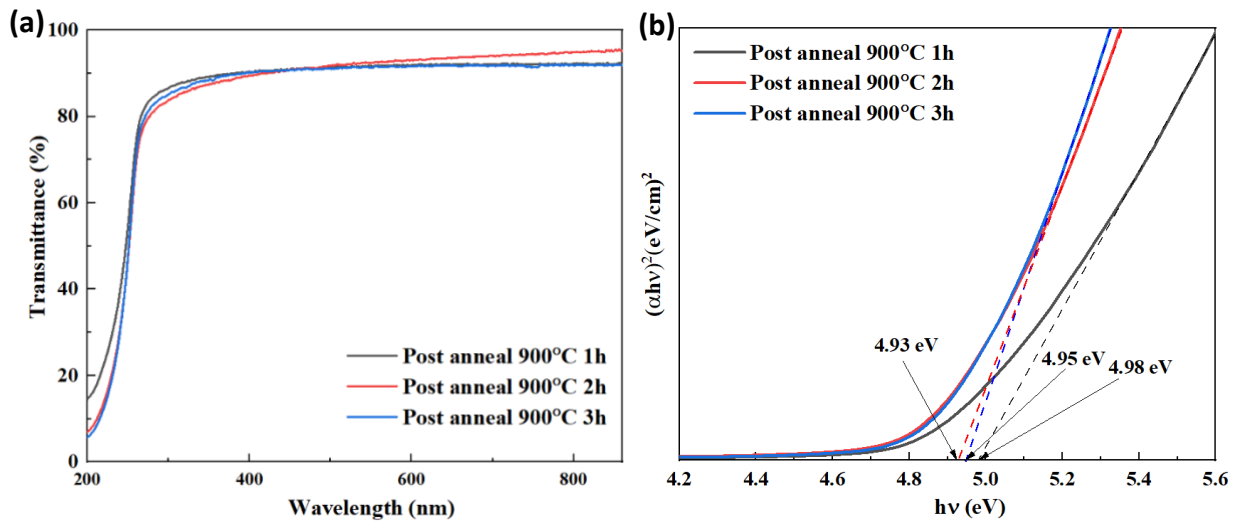


Fig. 6. (a) Optical transmission spectra and (b) bandgap estimation of β -Ga₂O₃ films post-annealed at 900 °C for 1, 2, 3 h















Conclusions

In this study we have systematically investigated the structural evolution and optic properties of spray-pyrolyzed β -Ga₂O₃ thin films as function of post-annealing duration (1–3 h at 900 °C). Increasing the post-annealing duration from 1 to 2 h enhances crystallinity, as evidenced by the growth of the average grain size from 8.15 to 14.06 nm, a reduction in the FWHM of the $\bar{2}02$ peak from 0.43 to 0.29°, and an increase in the RMS surface roughness from 0.94 to 1.87 nm. Concurrently, stress relaxation mediated by grain boundary migration narrows the optical bandgap from 4.98 to 4.93 eV. However, extending the post-annealing duration to 3 h further reduces the FWHM of the $\bar{2}02$ peak to 0.13°, while decreasing the average grain size to 11.44 nm and elevating the RMS surface roughness to 2.54 nm. This suggests that prolonged post-annealing triggers competitive grain growth, leading to heterogeneous coarsening into island-like crystalline domains.

The obtained results underscore that moderate post-annealing duration (2 h) optimizes crystallinity, whereas excessive thermal exposure compromises structural homogeneity. This study establishes that under the chosen experimental conditions, a 2-hour post-annealing at 900 °C represents an optimum for obtaining relatively smooth and solid β -Ga₂O₃ thin films. These findings advance the development of cost-effective,

scalable Ga₂O₃-based technologies, effectively bridging the gap between laboratory-scale synthesis and industrial applications.

CRediT authorship contribution statement

Xi Zhang  **Sc**: writing – original draft, conceptualization, investigation, data curation; **Dmitrii I. Panov**  **Sc**: data curation; **Vladislav A. Spiridonov**  **Sc**: data curation; **Natalia K. Kuzmenko** **Sc**: data curation; **Nikita D. Prasolov**  **Sc** : data curation; **Andrey Yu. Ivanov**  **Sc** : data curation; **Maksim V. Dorogov**  **Sc** : data curation; **Haoming Wei** **Sc** : investigation; **Dayong Jiang** **Sc**: investigation; **Dmitrii A. Bauman**  **Sc** : writing – review & editing, supervision; **Alexey E. Romanov**  **Sc** : supervision.

Conflict of interest

The authors declare that they have no conflict of interest.

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